



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE  
PATENT EXAMINING OPERATION

Applicant(s): Philippe STAIB

Serial No: 10/664,718

Group Art Unit: 2881

Filed: September 17, 2003

Examiner:

Att. Docket No.: B1180/20019

Confirmation No.: 4374

For: ELECTRON DIFFRACTION SYSTEM FOR USE IN PRODUCTION  
ENVIRONMENT AND FOR HIGH PRESSURE DEPOSITION TECHNIQUES (AS  
AMENDED)

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**INTRODUCTORY COMMENTS**

Prior to initial examination on the merits, please amend the above-identified application  
as follows:

Amendments to the Specification begin on page 2 of this paper.

Remarks/Arguments begin on page 3 of this paper.